Special Issue

Laser Micro/Nano Machining Technology

Message from the Guest Editors

Laser machining has emerged as a multidisciplinary frontier, capturing the interest of many researchers from different fields. However, there are still many challenges to overcome. This Special Issue of *Applied Sciences* on "Laser Micro/Nano Machining Technology" aims to give an overview of the latest developments in laser micro/nano machining. Topics of discussion include, but are not limited to, the exploration of new theory, method, technology, process, application, etc., which enable many breakthroughs in a great number of valuable research areas such as laser drilling/cutting/milling/writing, laser surface micro/nano texturing, laser micro/nano additive manufacturing, laser micro/nano welding and joining, etc. We hereby invite you to contribute original research and review articles.

Guest Editors

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Deadline for manuscript submissions

closed (20 June 2022)



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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multidimensional network.

Editor-in-Chief

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